

IEC QUALITY ASSESSMENT SYSTEM (IECQ)

covering Electronic Components,
Assemblies, Related Materials and Processes

For rules and details of the IECQ visit www.iecq.org

Schedule of Scope to Certificate of Approval

Independent Testing Laboratory

IECQ Certificate No.: IECQ-L ULTW 21.0003-02

CB Certificate No.: 50600408 ITL

Schedule Number: IECQ-L ULTW 21.0003-02-S Rev No.: 2 Revision Date: 2024/05/28 Page 1 of 2

Appendix-1 (50600408 ITL) Schedule of Scope to Certificate of Approval

Test Technology 測試項目	Test Method 測試標準		
Electrostatic Discharge (ESD) Test - Human Body Model (HBM) 人体模型静电敏感度试验	ANSI/ESDA/JEDEC JS-001 AEC-Q100-002 MIL-STD-883L-2017 method 3015.9 AEC-Q101-001-REV-A 2005 GJB 548C-2021 方法 3015.1		
Electrostatic Discharge (ESD) Test - Charged Device Model (CDM) (CDM)充电器件模型静电敏感度试验	ANSI/ESDA/JEDEC JS-002 AEC-Q100-011 AEC-Q101-005		
Latch-Up Test 集成电路闩锁测试	JEDEC JESD78F AEC-Q100-004		
Machine Model (MM) 机器模型	JESD22-A115C		
3D Optical Microscope (3D OM) 3 维数字光学显微镜	SHJF-WI-FA-031		
X-RAY microscope X-射线	SHJF-WI-FA-005		
Scanning Acoustic Tomography (SAT) 超音波扫描	SHJF-WI-FA-006		
Laser 镭射	SHJF-WI-FA-007		
InGaAs microscope 砷化镓微光显微镜	SHJF-WI-FA-019		

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Optical Beam Induced Resistance Change			

(OBIRCH) 镭射加热扫描定位	SHJF-WI-FA-012	
Thermal 热影像分析仪	SHJF-WI-FA-020	
IV cure tracer 曲线追踪仪测试	SHJF-WI-FA-010	
Probe 射频探针	SHJF-WI-FA-014	
Reactive-Ion Etching RIE 气体蚀刻	SHJF-WI-FA-022	
Grinder 研磨	SHJF-WI-FA-024	
Secondary Electron Microscope (SEM) 扫描电镜-8100	SHJF-WI-FA-029	
Focused Ion beam (FIB) 聚焦离子束线路修补-CKT	SHJF-WI-FA-029	
Dual Beam Focused Ion beam (Dual Beam FIB) 双束离子	SHJF-WI-FA-027	

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Technical Reviewer of DQS:		0	Date: 05/28/2024

